2829

15 2800 MAIL ROOM

Docket No. 197399US2

IN RE APPLICATION OF: Masahito KOBAYASHI, et al.

SERIAL NO: 09/667,502

FILED:

September 22, 2000

FOR:

PROBING METHOD AND PROBING APPARATUS

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an amendment in the above-identified application.

- No additional fee is required
- □ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
- Additional documents filed herewith:

Marked-up Copy of Amendment

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	23	MINUS	23	0	× \$18 =	\$0.00
INDEPENDENT	6	MINUS	6	0	× \$84 =	\$0.00
		□ MULTIPLE DEPENDENT CLAIMS + \$280 =				\$0.00
			TOTAL OF A	BOVE CALCU	JLATIONS	\$0.00
		□ Reduction by 50% for filing by Small Entity				\$0.00
		□ Recor	dation of Assignment	t	+ \$40 =	\$0.00
W. Alexander	91,				TOTAL	\$0.00

☐ A check in the amount of

is attached.

- Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

22850

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GJM:CDW:brf

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197399US2

## IN THE UNITE ATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

Masahito KOBAYASHI, et al.

: EXAMINER: KURIAN, R.

SERIAL NO.: 09/667,502

FILED: September 22, 2000

: GROUP ART UNIT: 2829

FOR: PROBING METHOD AND

PROBING APPARATUS

**AMENDMENT** 

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

In response to the Official Action dated February 27, 2002, please amend the aboveidentified application as follows:

## IN THE TITLE

Please delete the title in its entirety and add the following new title:

## PROBING METHOD AND PROBING APPARATUS IN WHICH STEADY LOAD IS APPLIED TO MAIN CHUCK

## IN THE SPECIFICATION

Page 2, please delete the paragraph beginning at line 4 and ending at line 15 and substitute therefor:

The loading chamber 11 is provided with a pair of tweezers 15 for use as a transportation mechanism for the wafers W. The tweezers 15 moves back and forth in the

8/limeta P.Walle 6-4-02